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Abstract

Method of Cleaving GaN/Sapphire for Forming Laser Mirror Facets

- 5 A method of fabricating a cleaved facet of a laser device having a substrate and at least one GaN-based layer formed upon a first surface of the substrate, said method including the following steps:
- cutting linear grooves into a second surface of the substrate, said grooves being in alignment with vertical planes of said substrate;
 - 10 and
 - cleaving said substrate and said at least one GaN-based layer along said vertical planes;
- wherein said cutting is effected by a laser beam from an external laser source.